REMARKS

The claims of Group I (Claims 1 - 27 and 34) are provisionally elected for examination in this application. However, reconsideration and withdrawal of the requirement is requested in light of the amendments made herein.

As amended, independent Claims 1 and 19 are directed to a system for processing a semiconductor substrate or wafer and, as such, are generic to both the * etching apparatus of Group I and the deposition apparatus of Group III. In addition, Claims 28 - 33 and 63 - 67 are being amended to make it clear that they are apparatus claims, rather than method claims as suggested by the Examiner.

The Commissioner is authorized to charge any fees required in this matter, including extension fees, to Deposit Account 50-2319, Order No. A-70179/ESW.

Respectfully submitted,

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